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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/075,640	02/13/2002	Michael Nuttall	500803.02 9841		
. 7590 11/28/2005			EXAMINER		
Paul F. Rusyn, Esq.			VU, DAVID		
DORSEY & W	HITNEY LLP	ART UNIT	PAPER NUMBER		
Suite 3400 1420 Fifth Avenue Seattle, WA 98101			2818		
			DATE MAILED: 11/28/2005		

Please find below and/or attached an Office communication concerning this application or proceeding.

					14.			
Office Action Summary		Application No.		Applicant(s)	, , ,			
		10/075,640		NUTTALL ET AL.				
		Examiner		Art Unit				
		DAVID VU		2818				
The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply								
A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely. - If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication. - Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). - Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b). Status								
1)⊠	Responsive to communication(s) filed on <u>05 A</u>	<u> August 2005</u> .						
2a) <u></u> ☐	This action is FINAL . 2b)⊠ Thi	is action is non-fi	nal.					
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.								
Disposition of Claims								
4) Claim(s) 38,45-59,62 and 63 is/are pending in the application.								
4a) Of the above claim(s) is/are withdrawn from consideration.								
·	5) Claim(s) is/are allowed. 6) ⊠ Claim(s) <u>38,45-59,62 <i>and</i> 63</u> is/are rejected.							
	Claim(s) is/are objected to.							
		r election require	ment					
8) Claim(s) are subject to restriction and/or election requirement. Application Papers								
	The specification is objected to by the Examine							
10)🖾 ¯	The drawing(s) filed on <u>13 February 2002</u> is/are				•			
	Applicant may not request that any objection to the							
11)☐ The proposed drawing correction filed on is: a)☐ approved b)☐ disapproved by the Examiner.								
If approved, corrected drawings are required in reply to this Office action.								
12) The oath or declaration is objected to by the Examiner.								
•	Inder 35 U.S.C. §§ 119 and 120	n mindty under 26	: ILS C S 110/o) (d) or (f)				
13) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).								
a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received.								
 2. Certified copies of the priority documents have been received in Application No 3. Copies of the certified copies of the priority documents have been received in this National Stage 								
 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received. 								
14) Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application).								
 a) ☐ The translation of the foreign language provisional application has been received. 15)☐ Acknowledgment is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121. 								
Attachment(s)								
2) Notic	e of References Cited (PTO-892) e of Draftsperson's Patent Drawing Review (PTO-948) nation Disclosure Statement(s) (PTO-1449) Paper No(s) _	4)		r (PTO-413) Paper No Patent Application (PT				

U.S. Patent and Trademark Office PTO-326 (Rev. 04-01) Application/Control Number: 10/075,640

Art Unit: 2818

DETAILED ACTION

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

1. Claims 38 and 45, 46, 49, 52-54, 57, 62 and 63 are rejected under 35 U. S. C. 102(e) as being anticipated by Teo et al. (US 6,204,137, herein after Teo).

Teo discloses in figs. 10-13 an in-process semiconductor structure, comprising: a monocrystalline silicon substrate 70; a substrate 70 including a plurality of transistors (fig. 13 and col. 6, lines 18-33), each transistor including a pair of active regions (source /drain region 110) formed within the substrate and having a channel region defined between each pair of active regions (source/drain region 110); a plurality of isolation oxide regions (STI structure 86) adjacent the active regions, each isolation oxide region 86 being positioned between adjacent active regions to isolate adjacent active regions; and at least one selectively formed single crystal contact 111 by epitaxially grown on each active region, each selectively formed single crystal contact 111 being isolated from single crystal contacts on adjacent active regions, each selectively formed single crystal

Application/Control Number: 10/075,640

Art Unit: 2818

contact 111 having a convex upper surface intersected by two sidewall surfaces, the two sidewalls surfaces being substantially perpendicular to an upper surface of the active region.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

2. Claims 47, 48, 50, 51, 55, 56, 58 and 59 are rejected under 35 U.S.C. 103(a) as being unpatentable over Teo (US 6,204,137) in view of White, Jr. et al., (US 6,130,102, herein after White, Jr.).

Teo discloses all claimed subject matter, but fails to expressly mention the substrate comprises silicon germanium or gallium arsenide.

White, Jr., in related text (col. 3, lines 26-31) discloses the substrate comprises silicon germanium or gallium arsenide. It would have been obvious to one of ordinary skill in the art at the time the invention was made for using the substrate materials as taught by White, Jr. since the material such as silicon germanium or gallium arsenide is recognized equivalent material for forming the substrate in a method of manufacturing a semiconductor device.

Art Unit: 2818

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to David Vu whose telephone number is (571) 272-1798. The examiner can normally be reached on Monday-Friday from 8:00am to 5:00pm. If attempt to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Nelms can be reached on (571) 272-1787. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR, Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

David Vu

November 18, 2005.